

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Ching-Tien Ma

Group Art Unit: 1756

Serial No.: 10/038,800

Examiner: Nicole M. Barreca

Filed: Dec. 31, 2001

In Response to Office Action
Dated: Dec. 12, 2003For: Method for Forming Via and Contact Holes with
Deep UV Photoresist

Attorney Docket No.: 67,200-549

Certificate of Facsimile Transmission

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Patent Office via facsimile no. (703) 972-9311 on the date shown below.

Date: Feb. 17, 2004

Kathy Dixon

REQUEST FOR RECONSIDERATIONCommissioner for Patents
Alexandria, VA 22313-1450

Dear Sir:

In response to a final Office Action mailed Dec. 12, 2003, please consider the following remarks.